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IN THE CLAIMS

The status of the claims as presently amended is as follows (with the changes highlighted):

- 1. (Currently Amended) A semiconductor integrated circuit device comprising:
 - a semiconductor substrate;
 - a first well of a first conductivity type formed in the semiconductor substrate:
 - a second well of the first conductivity type formed in the semiconductor substrate;
- a first lateral MOS transistor <u>having a source area</u>, a drain area, and a channel area formed between the source and drain areas thereof, the source, drain, and channel areas thereof being formed in said first well; and

a second lateral MOS transistor <u>having a source area</u>, a drain area, and a channel area formed between the source and drain areas thereof, the source, drain, and channel areas thereof <u>being formed in said second well</u>; and integrated in the semiconductor substrate,

wherein said second lateral MOS transistor has a lower threshold voltage than said first lateral MOS transistor and said first lateral MOS transistor has a smaller channel length than said second lateral MOS transistor; and

a punch-trough stopper area that surrounds asurrounding the source area and athe drain area of said first <u>lateral</u> MOS transistor <u>in the first well</u> and providesproviding a punch-through voltage resistance between said source area and said drain area <u>of said first lateral MOS</u> transistor.

wherein said second lateral MOS transistor has a lower threshold voltage than said first lateral MOS transistor, and

wherein the length of the channel area of said first lateral MOS transistor is smaller than the length of the channel area of said second lateral MOS transistor.

2. (Currently Amended) The semiconductor integrated circuit device according to Claim 1, wherein said first <u>lateral</u> MOS transistor comprises a digital circuit device and said second MOS transistor comprises an analog circuit device.

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- 3. (Currently Amended) The semiconductor integrated circuit device according to Claim 1, wherein a drain area of said second lateral MOS transistor is surrounded by has an offset drain area surrounding the drain area thereof and having a lower impurity concentration than the drain area thereof the second MOS transistor.
- 4. (Currently Amended) The semiconductor integrated circuit device according to Claim 3, further comprising a punch-through stopper area that surrounds asurrounding the source area of said second <u>lateral</u> MOS transistor and <u>providesproviding</u> a punch-through voltage resistance between the source area of said second <u>lateral</u> MOS transistor and said offset drain area.
- 5. (Original) The semiconductor integrated circuit device according to any of Claims 1 to 4, further comprising a bipolar transistor integrated in said semiconductor substrate.
- 6. (Original) The semiconductor integrated circuit device according to any of Claims 1 to 4, further comprising a diode integrated in said semiconductor substrate.
- 7. (Original) The semiconductor integrated circuit device according to any of Claims 1 to 4, further comprising a diffusion resistor integrated in said semiconductor substrate.
- 8. (Currently Amended) The semiconductor integrated circuit device according to Claim 1, wherein said source area of said first lateral MOS transistor includes a source LDD area and said drain area of said of said first lateral MOS transistor includes a drain side LDD area, and wherein the punch-through stopper area has a pocket structure that encloses the source side LDD area and the drain side LDD area.
- 9. (Previously Canceled)
- 10. (Previously Canceled)

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11. (Currently Amended) The semiconductor integrated circuit device according to Claim 1, further including a wherein said first well havinghas a lower impurity concentration than that of the punch-through stopper region areas formed in the substrate, wherein the punch-through stopper area is formed in the well.